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(54) ENGINE RECIPROCATIVE ROTATING MECHANISM AND METHOD FOR MANUFACTURING THE SAME

(57) A second dynamic vibration absorber 82 is higher in resonance frequency than a first dynamic vibration absorber 81. At least one of the resonance frequency of the first dynamic vibration absorber 81 or the resonance frequency of the second dynamic vibration absorber 82 is shifted from associated at least one of the first resonance frequency or the second resonance frequency such that a peak frequency of antiresonance occurring in a higher frequency region of the first dynamic vibration absorber 81 than the resonance frequency of the first dynamic vibration absorber 81 is substantially different from that of antiresonance occurring in a lower frequency region of the second dynamic vibration absorber 82 than the resonance frequency of the second dynamic vibration absorber 82.

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FIG. 4